



NA MEMS Standards Committee Meeting
SEMICON West Meetings – San Francisco, California
Monday, July 13, 2009, 3:00 pm - 5:00 pm

AGENDA

- A. Call to Order
 - 1) Introductions and Announcements
 - 2) Anti-Trust Reminder
 - 3) Intellectual Property Policy
 - 4) Effective Meeting Guidelines
 - 5) SEMI Staff Report
- B. Review and Approval of Prior Meeting Minutes and Action Items
 - 1) Spring Meetings '09
- C. Ballot Review
 - 1) Document 4717, Revision of SEMI MS2-0307, Test Method for Step-Height Measurements of Thin, Reflecting Films Using an Optical Interferometer with title change to Test Method for Step Height Measurements Of Thin Films
 - 2) Document 4718, Revision of SEMI MS4-1107, Test Method for Young's Modulus Measurements of Thin, Reflecting Films Based on the Frequency of Beams in Resonance
- D. Presentations
 - 1) Europe Liaison Report
 - 2) TF Reports
 - 2.1) International Terminology TF
 - 2.2) MEMS Materials Characterization TF
 - 2.3) Microfluidics TF
 - 2.4) MicroTube Interfaces WG
 - 2.5) Packaging TF
 - 2.6) Standard of Standards
 - 2.7) Wafer Bond TF
- E. Old Business
 - 1) Standards Roadmap Distribution for Global Input
 - 2) Recruitment and Motivation Plan
- F. New Business
 - 1) Wafer Bond Working Group Formation
 - 2) Review Charter and Discussion of Inclusion of Nano
 - 3) Liaison Other MEMS-related Groups in NA, Europe, Japan
- G. Action Items
 - 1) From this meeting
 - 2) Future Meetings
 - 2.1) Fall NA Standards Meetings in San Jose, CA area (Location and Date TBA)
- H. Adjourn